OPAMP内蔵小型変位センサ

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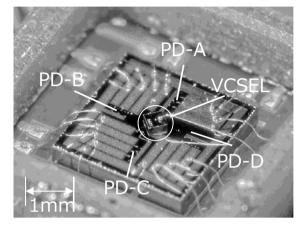






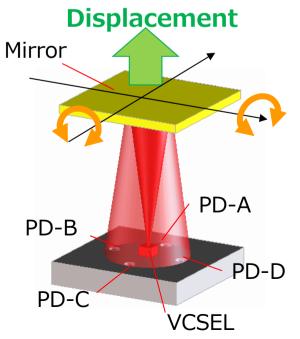
Micro Displacement Sensor

Micro displacement Sensor



Structure : Small & Simple Sensor chip size:3000×3000×700(µm) VCSEL(laser diode):850nm, 2.5mW Photodiodes(PDs): 3 PDs in each direction

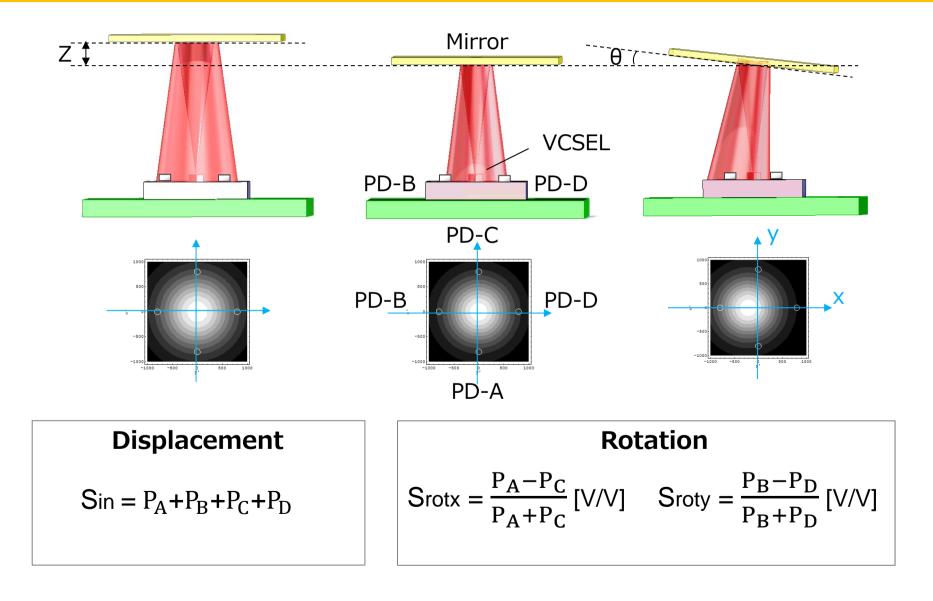
Measurement Displacement of the mirror Rotation of the mirror







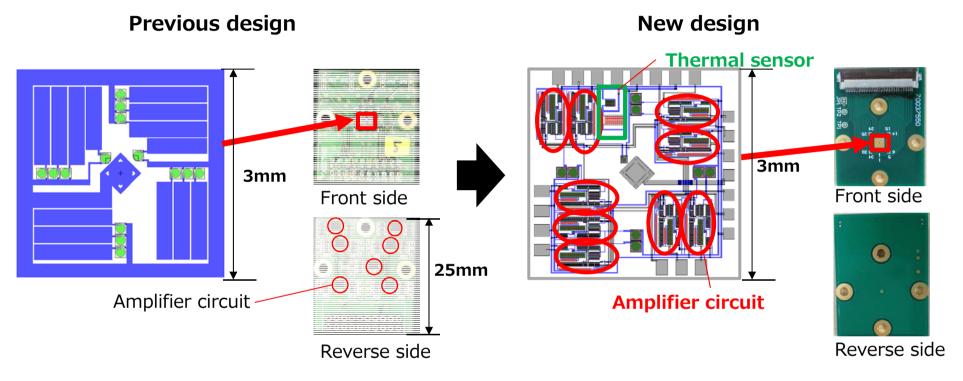
Principle







Chip design



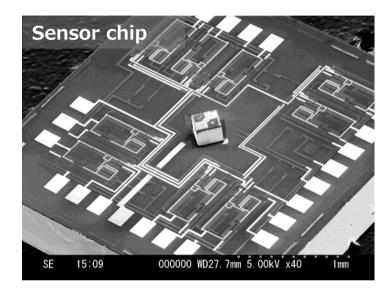
 3×4 PDs + 2 Monitor PDs Amplifier circuit on the substrate \rightarrow whole sensor size become large

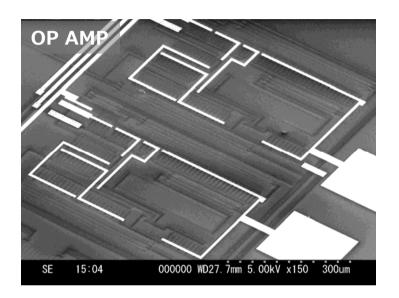
 2×4 PDs + 1 Monitor PD Amplifier circuit in the chip \rightarrow whole sensor size can be smaller \rightarrow improve the noise

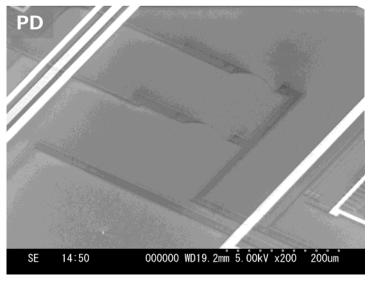


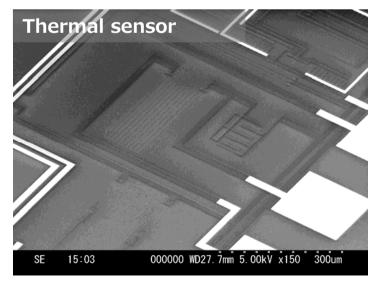


Fabricated sensor chip





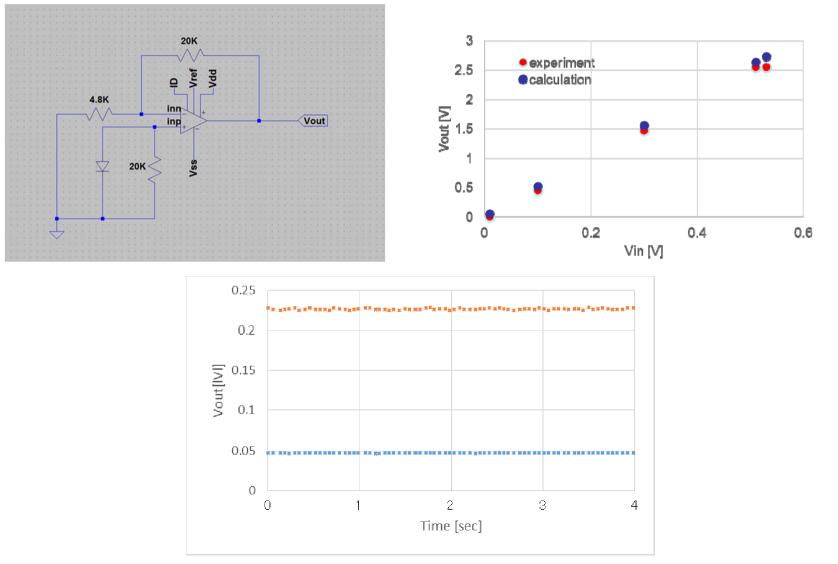








Evaluation of Op amp

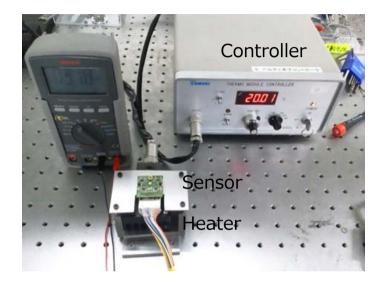


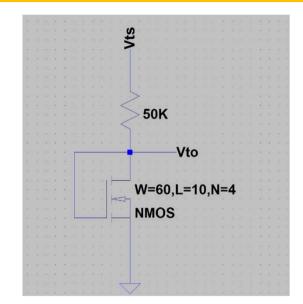
Output voltage of PD is amplified by OPAMP!

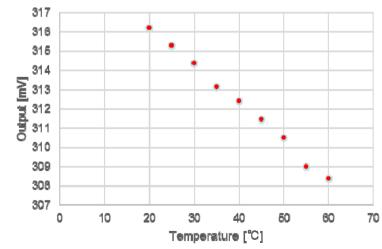




Evaluation of temperature sensor





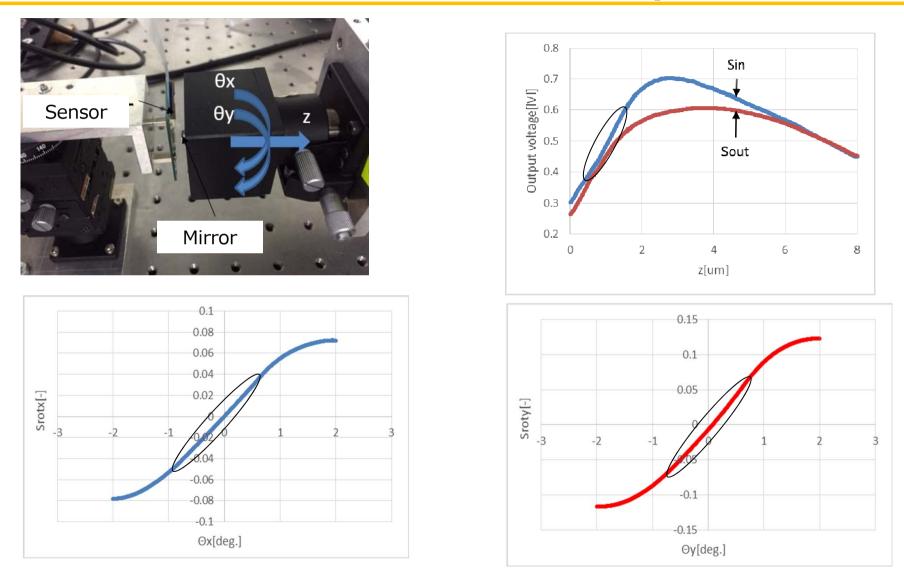


Thermal sensor can measure temperature of sensor chip !

KyushuUniversity The 5th Novel Device Design & Fabrication Contest in Hibikino



Evaluation of rotation and displacement



Sensor can measure displacement and rotation angle around two axes !





Conclusion

We fabricated displacement and rotation angle sensor. •Sensor chip size is 3000 [µm]×3000 [µm] and 700 [µm] in thickness. •OPAMP and Thermal sensor are integrated on this sensor chip.

Output voltage of PD is amplified using OPAMP. •Gain is about 4.9 [-] (non-inverting amplifier circuit)

Thermal sensor can measure tempreture of sensor chip. •The output changes linearly with measuring range of 20 [deg.] ~ 60 [deg.]

This Sensor can measure displacement and rotation angle around two axes.





Thank you for your kind attention.